

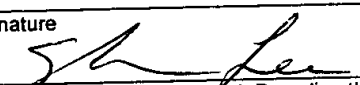
Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 09712-116001	Application No. 09/919,511
		Applicant Leslie L. Deck	
		Filing Date July 31, 2001	Group Art Unit 2778
Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR §1.98(b))			

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Patent Documents							
Examiner Initial	Desig. ID	Patent Number	Issue Date	Patentee	Class	Subclass	Filing Date If Appropriate
SL	AA	6,028,670	02/22/00	Deck			
	AB						

Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AC							

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
SL	AD	Kinoshita M. et al., "Optical Frequency-Domain Imaging Microprofilometry with a Frequency-Tunable Liquid-Crystal Fabry-Perot Etalon Device", <i>Applied Optics, Optical Society of America</i> , Vol. 38, No. 34, December 1, 1999, pp. 7063-7068
	AE	

Examiner Signature 	Date Considered 7/2/02
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

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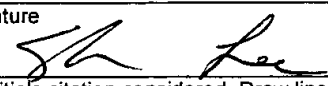
Sheet 1 of 1

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U.S. Patent Documents							
Examiner Initial	Desig. ID	Patent Number	Issue Date	Patentee	Class	Subclass	Filing Date If Appropriate
SL	AA	4,594,003	6/10/86	Sommargren			

Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
SL	AB	L. Deck; "Measurements using Fourier-Transform Phase Shifting Interferometry", Proc. ASPE 25, 115-118 (2001)
SL	AC	L. Deck; "Multiple Surface Phase Shifting Interferometry", Proc. SPIE, 4451, 424-430 (2001)
SL	AD	L. Deck and J.A. Soobitsky, "Phase-shifting via wavelength tuning in very large aperture interferometers," Proc. SPIE, 3782-58, 432-442, 1999
SL	AE	L. Deck; "Simultaneous Multiple Surface Measurements using Fourier-Transform Phase Shifting Interferometry, in: 4th International workshop on automatic processing of fringe patterns", Fringe 2001, Elsevier, Paris, (2001), 230-236
SL	AF	P. de Groot, "Chromatic dispersion effects in coherent absolute ranging," Opt. Lett., Vol. 17, pp. 898-900, 1992
SL	AG	Peter de Groot, "Derivation of algorithms for phase-shifting interferometry using the concept of a data-sampling window," Applied Optics, Vol. 34, p. 4723, 1995
SL	AH	Peter de Groot, "Measurement of transparent plates with wavelength-tuned phase-shifting interferometry," Applied Optics, Vol. 39, No. 16, pp. 2658-2663, 2000
SL	AI	Klaus Freischlad, "Fourier Analysis of Phase Shifting Algorithms," Proc. SPIE Vol. 3407, pp. 73-85, 1998
SL	AJ	K. Freischlad, "Large flat panel profiler," Proc. SPIE 2862, pp. 163-171, 1996
SL	AK	J.E.Greivenkamp and J.H.Bruning, "Phase shifting interferometry," Optical Shop Testing, D. Malacara, pp. 501-598, J.Wiley, New York, 1992
SL	AL	Susumu Kuwamura and Ichirou Yamaguchi, "Wavelength scanning profilometry for real-time surface shape measurement," Appl. Opt., 36, 4473-4482 (1997)
SL	AM	Okada et al., "Separate measurements of surface shapes and refractive index inhomogeneity of an optical element using tunable-source phase shifting interferometry," Applied Optics, Vol. 29, No. 22, pp. 3280-3285, 1990
SL	AN	M. Suematsu and M. Takeda, "Wavelength-shift interferometry for distance measurements using Fourier transform technique for fringe analysis," Applied Optics, Vol. 30, No. 28, pp. 4046-4055, 1991

Examiner Signature 	Date Considered 7/2/02
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